

ABSTRACTA MEASUREMENT METHOD AND MEASUREMENT APPARATUS

- 5 Measurement methods and measurement apparatus are described and claimed, which employ an interferometer arranged for form patterns of interference fringes. One aspect of the invention provides a measurement method comprising the steps of arranging an interferometer to form a first interference fringe pattern
- 10 comprising at least ten interference fringes; recording an image of said first interference fringe pattern; perturbing an optical path in the interferometer to form a second interference fringe pattern comprising at least ten interference fringes; and combining an image of said second interference fringe pattern
- 15 with the recorded image of the first interference fringe pattern to produce a further image comprising a moiré fringe pattern arising from a difference or differences between the first and second interference fringe patterns.